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SHIGA7.016APC PATENT

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**Applicant** 

Hada et al.

Int'l Appl. No.

PCT/JP2003/015347

Int'l Filing Date

December 1, 2003

For

METHOD OF FORMING RESIST PATTERN, POSITIVE RESIST COMPOSITION, AND LAYERED

**PRODUCT** 

Examiner

Unknown

Group Art Unit

Unknown

## PRELIMINARY AMENDMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

Prior to examination on the merits, please amend the present application.

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks/Arguments begin on page 7 of this paper.